NIT-215

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

S. KONDO et al

Serial No. 09/637,570

Group Art Unit: 2812

Filed: August 14, 2000

Examiner: Ha T. Nguyen

For: POLISHING METHOD, METALLIZATION FABRICATION

METHOD, METHOD FOR MANUFACTURING SEMICONDUCTOR

DEVICE AND SEMICONDUCTOR DEVICE

## AMENDMENT

Commissioner for Patents Washington, D.C. 20231

Sir:

In response to the Office Action dated November 15,

2002, please amend the above-identified application as

FAX RECEIVED

follows.

MAR 1 7 REC'D

**TECHNOLOGY CENTER 2800**